

High Accuracy, Miniature Pressure Sensor for Very High Temperatures, Phase I

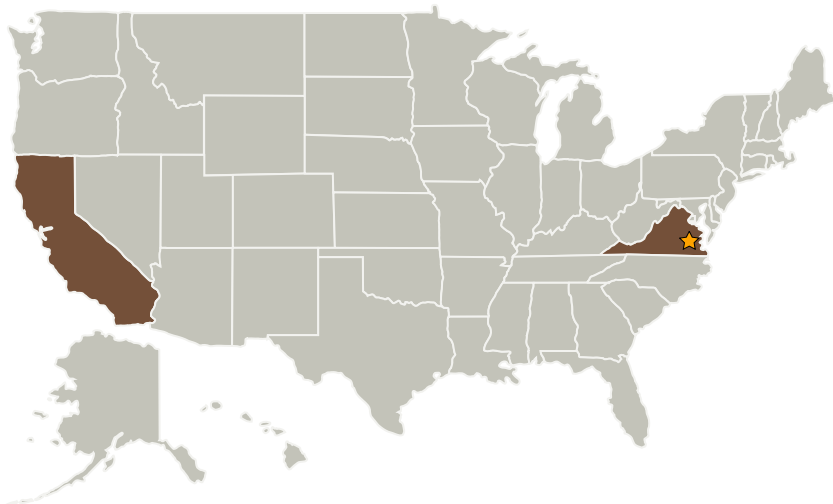
Completed Technology Project (2004 - 2004)



Project Introduction

SiWave proposes to develop a compact, low-cost MEMS-based pressure sensor for very high temperatures and low pressures in hypersonic wind tunnels. Most currently available pressure sensors use a micromachined diaphragm whose deflection is dependent on pressure. The deflection is typically measured by techniques that are not suited for high temperature ($> \sim 200^\circ\text{F}$) operation, or that are insensitive to small ($< \sim 0.1$ psi) pressure changes. As a result, no commercial sensors cover 0-5 PSI at temperatures above 200°F , despite the fact that this regime is important for NASA's hypersonic wind tunnel testing programs, as well as for hypersonic flight avionics. SiWave's proposed pressure sensor is a novel implementation of squeeze film resonant sensor approach, with a sophisticated multi-element resonator designed for very high Q and temperature stability, made from silicon carbide. The device is controlled by distant external electronics. These innovative features result in a sensor with high accuracy (0.005 PSI) over an unprecedented temperature range (up to 650°F), and the potential to be manufactured in dense arrays.

Primary U.S. Work Locations and Key Partners



Organizations Performing Work	Role	Type	Location
★ Langley Research Center (LaRC)	Lead Organization	NASA Center	Hampton, Virginia
Siwave, Inc.	Supporting Organization	Industry	Arcadia, California



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Organizational Responsibility

Responsible Mission Directorate:

Space Technology Mission Directorate (STMD)

Lead Center / Facility:

Langley Research Center (LaRC)

Responsible Program:

Small Business Innovation Research/Small Business Tech Transfer

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Primary U.S. Work Locations

California

Virginia

Project Management

Program Director:

Jason L Kessler

Program Manager:

Carlos Torrez

Principal Investigator:

Darrell Harrington

Technology Areas

Primary:

- TX08 Sensors and Instruments
 - └ TX08.3 In-Situ Instruments and Sensors
 - └ TX08.3.4 Environment Sensors